

U.S. Department of Commerce, Patent and Trademark Office		Atty Docket No.	Serial No.
		PSI004-1C US	Unknown
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)		Applicant(s)	
		Kwon, joonhyung;	
		Filing Date	Group
		HEREWITH	unknown

U.S. Patent Documents							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
Dm	AA	Re. 35,514	5/20/97	Albrecht et al	250	216	
Dm	AB	5,103,095	4/7/1/92	Elings et al	250	306	
Dm	AC	5,157,251	10/20/92	Albrecht et al	250	216	
Dm	AD	5,376,790	12/27/94	Linker et al	250	306	
Dm	AE	5,714,756	2/3/98	Park et al	250	306	
Dm	AF	5,854,487	12/29/98	Braunstein et al	250	306	
Dm	AG	5,877,891	3/2/99	Park et al	359	372	
Dm	AH	5,939,719	8/17/99	Park et al	250	306	
Dm	AI	6,057,546	5/2/00	Braunstein et al	250	306	
Dm	AJ	6,057,547	5/2/00	Park et al	250	307	
Dm	AK	6,185,991 B1	2/13/01	Hong et al	73	405	
Dm	AL	6,310,342 B1	10/30/01	Braunstein et al	250	306	

Foreign Patent Documents							Translation	
		Document	Date	Country	Class	Subclass	Yes	No

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

AQ	Binnig G., et al, "Atomic Force Microscope", <i>Physical Review Letters</i> , Vol 56, No. 9, 3 March 1986 pages 930-933
AR	Hansma, P.K., et al, "A new, optical-lever based atomic force microscope", <i>J. Appl. Phys.</i> , 76(2) 15 July 1994, American Institute of Physics, pages 796-799
AS	Meyer, Gerhard et al, "Erratum: Novel optical approach to atomic force microscopy", <i>Appl. Phys. Lett.</i> 53(24), 12 December 1988, American Institute of Physics, pages 2400-2402
AT	"Dimension 3100 Scanning Probe Microscope The Most Versatile SPM Ever Manufactured", www.di.com/Products/Dim/3100/D3100Main.html , Digital Instruments, Vecco Metrology Group ©1998-2001, print date 12/17/2001, 4 pages

Examiner *Dm* Date Considered *70 out w dark*

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

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	AU						
	AV						
Foreign Patent Documents							
							Translation
	AW						Yes
	AX						No
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)							
AY	"Dimension 3100 Sean Techniques Unparalleled Power and Versatility", www.di.com/Products/Dim/3000/D31_seantechiques.html, Digital Instruments Veeco Metrology Group, ©1998-2001, print date 12/17/2001, 2 pages						
AZ	Babcock, K.L. et al., "Phase Imaging: Beyond Topography", Digital Instruments, 3 pages (believed to be prior to 2-15-02)						
BA	"AutoProbe CP Research AP 2001", ThermoMicroscopes, 5 pages (believed to be prior to 2-15-02)						
BB	"AutoProbe CP Research Scanning Probe Microscope", ThermoMicroscopes, 4 pages (believed to be prior to 2-15-02)						
BC	"AutoProbe MSE AP-5001", ThermoMicroscopes, 4 pages (believed to be prior to 2-15-02)						
BD	AutoProbe MS™ Scanning Probe Microscope, Microscopes Veeco Metrology Group, 2001 © TM Microscopes, Vecco, 4 pages						
BE	"TappingMode Imaging: Application and Technology", www.di.com/AppNotes/TapMode/TapModeMain.html, Digital Instruments, Vecco Metrology Group, ©1995-2001, Digital Instruments, print date 12/17/2001, 5 pages						
BF	"NanoScope Vertical Engage Scanner", www.di.com/Products/MultiPVScanner.html, Digital Instruments Vecco Metrology Group, ©1996-2001, Digital Instruments, print date 12/17/2001, 1 page						
BG	"NanoScope Multivide Scanning Probe Microscope", www.di.com/products/Multi/MMALone.html, Digital Instruments Vecco Metrology Group, © 1996-2001, Digital Instruments, 8 page						
Examiner <i>CDL82</i>	Date Considered <i>20 Oct 2004</i>						
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U.S. Patent Documents								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
	BH							
Foreign Patent Documents								
							Translation	
	BI						Yes	No
	BJ							
	BK							
	BL							
	BM							
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)								
BN	"NanoScope® MultiMode™ SPM The World's Highest Resolution SPM", www.di.com/Products/Multi/MMMain.html , Digital Instruments Veeco Metrology Group, ©1995-2001, Digital Instruments, print date 12/17/2001 7 pages							
BO	"Products", Digital Instruments, Veeco Metrology Group Products, www.di.com/products2/products_all.html , print date 12/17/01, 5 pages							
BP	"AutoProbe CP Research The Most Flexible Research SPM", www.theermicro.com/products/cp.htm , Microscopes Veeco Metrology Group, ©2001, print date 12/17/01, 2 pages							
BQ	Manalis, S. R., et al, "High-speed atomic force microscopy using an integrated actuator and optical lever detection", Rev. Sci. Instrum. 67(9), September 1996, pages 3294-3297							
BR	"The Dimension™ 5000 Scanning Probe Microscope", Digital Instruments, 8 pages (believed to be prior to 2-15-02)							
BS	"The Dimension™ 3000 Scanning Probe Microscope", Digital Instruments, 6 pages (believed to be prior to 2-15-02)							
BT	"The Enhanced Dimension™ 3100 Scanning Probe Microscope", Digital Instruments, 1 page (believed to be prior to 2-15-02)							
BU	"Microlevers™ General Purpose Cantilevers", Park Scientific Instruments ©1998, 1 page (believed to be prior to 2-15-02)							
Examiner			Date Considered		20 October 2004			
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U.S. Department of Commerce, Patent and Trademark Office		Application No.:	Unknown
		Filing Date:	Unknown
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)		First Named Inventor:	Joonhyung Kwon
		Group Art Unit:	Unknown
		Examiner Name:	Unknown
		Confirmation No.:	Unknown
		Attorney Docket No.:	PSI004-1C US

U.S. Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
<i>Dm</i>	1.	6,144,028 A	11-2000	Kley, Vic B.	250	234	
<i>Dm</i>	2.	5,705,814 A	01/1998	Young et al.	250	306	
<i>Dm</i>	3.	2002/0148955 A1	10/2002	Hill, Henry A.	250	234	
<i>Dm</i>	4.	5,939,709 A	08/1999	Ghislain et al.	250	216	
<i>Dm</i>	5.	5,672,816 A	09/1997	Park et al.	73	105	
<i>Dm</i>	6.	5,210,410 A	05/1993	Barrett, Robert	250	234	
<i>Dm</i>	7.	6,169,281 B1	01/2001	Chen et al.	250	234	
<i>Dm</i>	8.	5,948,972 A	09/1999	Samsavar et al.	73	105	

Foreign Patent Documents

Translation

		Document	Date	Country	Class	Subclass	Yes	No

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

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